Methods and Systems for Processing a Substrate Using A Dynamic Liquid Meniscus

ABSTRACT OF THE DISCLOSURE

A system and method of moving a meniscus from a first surface to a second surface includes forming a meniscus between a head and a first surface. The meniscus can be moved from the first surface to an adjacent second surface, the adjacent second surface being parallel to the first surface. The system and method of moving the meniscus can also be used to move the meniscus along an edge of a substrate.

Fig. 5C